Reliability and Performance Analysis of a Complex Manufacturing System with Inspection facility using Copula Methodology

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Abstract

This paper deals with the assessment of various reliability factors of a real-life manufacturing system having inspection facility. This multistate manufacturing system have five workstations those are connected in series configuration as: W_1 , W_2 , W_3 , W_4 , W_5 . Workstations W_2 and W_4 has the configuration 2-out-of-3: G and 1-out-of-3: F. Due to failure of the any of the workstation, whole manufacturing system can completely fail. Apart from this machine failure can also make system down. To avoid sudden failure in the system pre-emptive maintenance strategy has been adopted. This is a corrective maintenance action before a failure occurs and scheduled during off days. Risk analysis is done because of fault of W_5 workstation in material quality inspection. Probability distributions like exponential time distribution is followed by all failures and general time distribution by all repairs. To study the probabilistic behavior of the system in different possible transition states, Markov process have been used. Supplementary variable technique and copula method of finding joint probability distribution have been used to obtained various reliability features such as steady state behavior of the system, reliability function, availability, Mean time to failure, sensitivity analysis and profit analysis.

Keywords: Reliability analysis, Mean time to failure, Availability, Sensitivity analysis, Risk analysis

1. Introduction

Nowadays, Due to the globalization of the market and business, a lot of problems related to manufacturing industries like delays in product delivery, machine failure, cancellation of demand, etc. are encountered by the industries daily. Therefore, reliability and availability analysis are important for the performance analysis of discrete manufacturing systems. A lot of work has been done to discuss reliability measures of manufacturing systems using different approaches [1, 3, 5, 6 and 7]. Here, a concept of making a methodical approach to analyze a failure-free system for a manufacturing industry is developed for a practical period [9].

The objective of this work is to assess the performance and risk analysis of a manufacturing system under different operating conditions. This multistate manufacturing system contains five workstations that are connected in the series configuration as W_1 , W_2 , W_3 , W_4 , and W_5 . Workstation W_1 consists of the raw material supplied by a merchant or vendor for making finished goods. At workstation W_2 material provided by workstation W_1 is transformed into welded usable form and small and big components are used to make the final product. Later on, these welded components

are sent to workstation W₃ for the dye or tint process. Workstation W₄ plays a vital role in this complex manufacturing system as the finished product assembles here only by connecting and arranging equipped components in logical order received from workstation W₃. At last, before

sending the finished product to suppliers in the market, it goes through the inspection process at workstation W₅ for quality inspection. On the workstations W₂ and W₄, three machines are involved in performing the same task connected parallelly. These workstations follow 2-out -of-3:G and 1out-of-3:F conformations, which means that for the fully operational stage of the system in which it can achieve the required target, it is essential that at least two machines of workstation W_2 and W_4 are in working condition otherwise in the opposite case the system fails [2]. Along with this, Machine failure is also considered which may be major or minor. To get maximum reliability, two groups of repairmen are involved in repairing the system according to their knowledge and skills. Here, a joint probability distribution is obtained using copula methodology when both groups are involved in repairing the system at the same time [4 and 8]. After getting finished goods, product inspection is done by workstation W₅. Here, any fault or ignorance in the inspection of the product can take the system into a risk state that can cause system failure. For example, if a technical fault is there in final assembled product due to wrong assembly or material use which can result in a failure after a certain period of use of the product or in certain climatic conditions, also the product have been not tested for that period or under that climatic conditions. The transition state diagram and state specification of the considered system are shown in figure-1 and table-1 respectively. The figure-1 shows positive transition intensities, and the transition probabilities for time Δ are proportional to the intensities, the remaining transition probabilities for time Δ are equal to $o(\Delta)$.

2. Notations

$P_0(t)$:	Denotes Probability at time t when the system is in initial state S_0
Pi (k, t)	:	Denotes the probability of system getting in breakdown state because of failure of the i th workstation at time t, also elapsed repair time considered in between k and k+ Δ , where i= 1, 2, 3, 4, 5, M, QR, and k \in [0, + ∞)
W1/W2/W3/ W4/W5	:	Workstation 1 to Workstation 5
K	:	Elapsed repair time, where $k \in [0, +\infty)$
ψ_{1W} / ψ_{1A}	:	The Showing Failure rate of the one machine of the Workstation 2/4.
$\psi_{\scriptscriptstyle M}$:	Machine failure rate
$P_{1W}(t)$:	Showing the probability of 2-out -of-3: G state of workstation 2 i.e. system is in fully operational mode even after one machine of workstation 2 is failed and rest two are in working condition
$P_{1A}(t)$:	Showing the probability of 2-out -of-3: G state of workstation 4 i.e. system is in fully operational mode even after one machine of workstation 4 is failed and rest two are in working condition
ψ_i	:	The General failure rate of i th workstation, where i= 1, 2, 3, M, 4, 5.

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$\phi_i(k)$:	Showing repair rate of i th workstation betwee where i= 1, 2, 3, 4, 5, M, OR, and $k \in [0, +\infty)$	en the time interval (k, k+ Δ),
γ _Q :	Showing risk rate or the factor which indicate consideration which can lead the system into th	es the level of risk taken into e risk stage
Pi, W (k, t) :	Shows the probability of the failed state of the sworkstation from the state S ₂ when one mach working. Elapsed repair time for the i th subsyste i=1, 3, 4 and $k \in [0, +\infty)$	system due to failure of the i^{th} ine of workstation W_2 is not m lies between (k, k+ Δ), where
Pi, A (k, t) :	Shows the probability of the failed state of the sworkstation from the state S ₂ when one mac working. Elapsed repair time for the i th subsyste i= 1, 2, 3 and k \in [0, + ∞).	system due to failure of the i th thine of workstation 4 is not m lies between (k, k+ Δ), where
$P_{QR}(q, t)$:	Shows the probability at time t when the system in inspection at the workstation 5	is in the risk due to ignorance
K1, K2 :	Profit and service cost per unit time respectively	

Also, consider $u_1 = e^r$ and $u_2 = \phi_M(r)$, according to Gumbel-Hougaard copula methodology the joint probability distribution is given by

$$\phi_{M} = \exp\left[r^{\theta} + \left[\log\phi_{M}(r)\right]^{\theta}\right]^{1/\theta}.$$

2.1. Assumptions

For reliability analysis of this manufacturing system, the following assumptions are taken into consideration.

- All the workstations are fully operational at t=0.
- Failures follow exponential time distribution and are statistically independent while repairs follow arbitrary time distributions.
- Repaired workstations are assumed like in good working conditions.
- Workstations 2 and 4 follow 2-out-of-3: G and 1-out-of-3: F conformation.
- It is also considered that the manufacturing system can fail due to any mechanical failure that may be major or minor or both at the same time. Here joint probability distribution is used to solve these failures using the copula methodology [6]. The whole system can also fail due to machine failures that may be either major or minor or both.

2.2. State specification

Table -1 shows the state specification of the transition diagram-1

States	Description	System State
S0	The system is in the fully operational stage.	G
S1	The system is in the failed state due to the failure of the workstation W_1 .	Fr
S2	The system is in a working state when workstation W ₂ is in 2-out-of-3: G configuration.	G
S3	Due to the failure of workstation W ₃ , the whole system is in the failed state.	Fr
S4	The system is in a working state when workstation W4 is in 2-out-of-3: G configuration.	G
S5	Due to machine failure, the whole system is in a breakdown condition.	Fr
S6	System is working at high risk due to negligence of the workstation W_5 .	Rs
S7	The system is in inoperable condition from the risk state i.e. S ₆ due to ignorance in the inspection.	Fr
S8	The system is in inoperable condition from the state S_2 as workstation W_1 is unable to work due to some vendor issues.	Fr
S9	The system is in inoperable condition from the state S ₂ due to the failure of workstation W4.	Fr
S10	The system is in the failed state from the state S ₂ because workstation W ₂ follows 1-out-of-3: F configuration.	Fr
S11	The system is inoperable due to the not functioning of workstation W_3 .	Fr
S12	The system is in inoperable condition from the state S4 due to the failure of workstation W1.	Fr
S13	The system is inoperable from the state S4 due to the failure of the workstation W2.	Fr
S14	The system is inoperable from the state S4 due to the failure of the workstation W3.	Fr
S15	The system is inoperable from the state S4 due to the failure of the workstation W4.	Fr

Table 1: State specification table



3. Formulation of the mathematical model

Following integro- differential equations which satisfying the model are obtained after probabilistic considerations and limiting process:

$$\begin{bmatrix} \frac{d}{dt} + \psi_{1A} + \psi_{1W} + \psi_{V} + \psi_{M} + \psi_{p} + \gamma_{Q} \end{bmatrix} P_{0}(t) = \int_{0}^{\infty} \phi_{V}(x) P_{V}(x,t) dx + \int_{0}^{\infty} \phi_{p}(y) Pp(y,t) dy + \int_{0}^{\infty} \phi_{M}(r) P_{M}(r,t) dg + \int_{0}^{\infty} \phi_{Q}(q) P_{Q}(q,t) dq + \int_{0}^{\infty} \phi_{A}(g) P_{A}(g,t) dg + \int_{0}^{\infty} \phi_{W}(u) P_{W}(u,t) du + \int_{0}^{\infty} \phi_{Q}(h) P_{Q}(h,t) dh$$

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial x} + \phi_{V}(x) \end{bmatrix} P_{V}(x,t) = 0$$
(1)

$$\begin{bmatrix} \partial t & \partial x & H(t,y) \end{bmatrix} V(t,y) = 0$$

$$\begin{bmatrix} \partial \\ \partial t &+ \partial \\ \partial y &+ \phi_p(y) \end{bmatrix} P_p(y,t) = 0$$
(3)

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial r} + \exp\left[r^{\theta} + \left\{\left[\log\phi_{M}(r)\right]\right\}^{\theta}\right]^{1/\theta} \end{bmatrix} P_{M}(r,t) = 0$$

$$\begin{bmatrix} \partial & \partial \\ \partial & 0 \end{bmatrix}$$
(4)

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial q} + \psi_{Q} + \phi_{QR}(q) \end{bmatrix} P_{QR}(q, t) = 0$$

$$\begin{bmatrix} \partial & \partial \\ \partial & \partial \end{bmatrix}$$
(5)

$$\left[\frac{\partial}{\partial t} + \frac{\partial}{\partial h} + \phi_{Q}(h)\right] P_{Q}(h,t) = 0$$
(6)

$$\begin{bmatrix} \frac{d}{dt} + \psi_A + \psi_W + \psi_V + \psi_M + \psi_p + \gamma_Q \end{bmatrix} P_{1w}(t) = \int_0^\infty \phi_V(x) P_{VW}(x, t) dx + \int_0^\infty \phi_A(g) P_{AW}(g, t) dg + \int_0^\infty \phi_P(y) P_{PW}(y, t) dy + \int_0^\infty \phi_P(y) P_{AW}(g, t) dg + \int_0^\infty \phi_P(y) P_{AW}(y, t) dy +$$

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial x} + \phi_V(x) \end{bmatrix} P_{VW}(x,t) = 0$$
(7)

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial g} + \phi_A(g) \end{bmatrix} P_{AW}(g,t) = 0$$
⁽⁸⁾
⁽⁹⁾

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial y} + \phi_p(y) \end{bmatrix} P_{p_W}(y,t) = 0$$
(10)

$$\begin{bmatrix} \frac{\partial}{\partial t} + \frac{\partial}{\partial u} + \phi_W(u) \end{bmatrix} P_W(u,t) = 0$$
(10)
(11)

$$\left[\frac{d}{dt} + \psi_{A} + \psi_{W} + \psi_{V} + \psi_{M} + \psi_{p} + \gamma_{Q}\right] P_{1A}(t) = \int_{0}^{\infty} \phi_{V}(x) P_{VA}(x,t) dx +$$
(11)

$$\int_{0}^{\infty} \phi_{p}(y) P_{P_{A}}(y,t) dy + \int_{0}^{\infty} \phi_{W}(u) P_{WA}(u,t) du + \psi_{1A} P_{0}(t)$$
(12)

$$\left[\frac{\partial}{\partial t} + \frac{\partial}{\partial x} + \phi_V(x)\right] P_{VA}(x,t) = 0$$
(13)

$$\left[\frac{\partial}{\partial t} + \frac{\partial}{\partial y} + \phi_p(y)\right] P_{P_A}(y,t) = 0$$
(14)

$$\left[\frac{\partial}{\partial t} + \frac{\partial}{\partial u} + \phi_{W}(u)\right] P_{WA}(u,t) = 0$$
(15)

$$\left[\frac{\partial}{\partial t} + \frac{\partial}{\partial g} + \phi_A(g)\right] P_A(g,t) = 0$$
(16)

3.1 Boundary conditions

$$P_{V}(0,t) = \psi_{V} P_{0}(t)$$
(17)

$$P_{p}(0,t) = \psi_{p}P_{0}(t)$$
(18)

$$P_{M}(0,t) = \psi_{M} P_{0}(t)$$
⁽¹⁹⁾

$P_{QR}(0,t) = \gamma_{Q} [P_{0}(t) + P_{A}(t) + P_{W}(t)]$	(20)
$P_Q(0,t) = \psi_Q P_{QR}(t)$	(21)

$$P_{VW}(0,t) = \psi_V P_W(t) \tag{22}$$

$$P_{AW}(0,t) = \psi_A P_W(t) \tag{23}$$

$$P_{PW}(0,t) = \psi_{p} P_{W}(t)$$
(24)

$$P_W(0,t) = \psi_W P_W(t)$$

$$P_W(0,t) = \psi_W P_W(t)$$
(25)

$$P_{VA}(0,t) = \Psi_V P_A(t)$$

$$P_{VA}(0,t) = \psi_V P_A(t)$$
(26)

$$P_{pA}(0,t) = \psi_{p}P_{p}(t)$$

$$P_{pA}(0,t) = \psi_{p}P_{p}(t)$$
(27)

$$P_{WA}(0,t) = \psi_W I_A(t)$$

$$P_A(0,t) = \psi_W P_A(t)$$
(28)

$$P_A(0,t) = \psi_A P_A(t) \tag{29}$$

3.2 Initial Condition

$$P_0(0) = 1$$
, otherwise zero. (30)

After solving equations (1) to (16), using initial and boundary conditions by taking Laplace transform, one can obtain following up and down probabilities of the system.

$$\overline{P_0}(s) = \frac{1}{K(s)}$$
(31)

$$\overline{P_{1w}}(s) = \frac{B(s)}{K(s)}$$
(32)

$$P_{1A}(s) = \frac{H(s)}{K(s)}$$

$$(33)$$

$$\overline{P_{\nu}}(s) = \frac{\psi_{\nu}}{K(s)} J_{\nu}(s)$$
(34)

$$\overline{P_P}(s) = \frac{\psi_P}{K(s)} J_P(s)$$
(35)

$$\overline{P_M}(s) = \frac{\psi_M}{K(s)} J_M(s)$$
(36)

$$\overline{P_{QR}}(s) = \frac{\gamma_Q}{K(s)} \left[1 + B(s) + A(s) \right] J_{QR}(s)$$
(37)

$$\overline{P_{Q}}(s) = \frac{\gamma_{Q} \psi_{Q}}{K(s)} \left[1 + A(s) + B(s) \right] J_{QR}(s) J_{Q}(s)$$
(38)

$$\overline{P_{VW}}(s) = \frac{\psi_V B(s)}{K(s)} J_V(s)$$
(39)

$$\overline{P_{PW}}(s) = \frac{\psi_P B(s)}{K(s)} J_P(s)$$
(40)

$$\overline{P_{AW}}(s) = \frac{\psi_A B(s)}{K(s)} J_A(s)$$
(41)

$$\overline{P_W}(s) = \frac{\psi_W B(s)}{K(s)} J_W(s)$$
(42)

$$\overline{P_{VA}}(s) = \frac{\psi_V A(s)}{K(s)} J_V(s)$$
(43)

$$\overline{P_{PA}}(s) = \frac{\psi_P A(s)}{K(s)} J_P(s)$$
(44)

$$\overline{P_{WA}}(s) = \frac{\psi_W A(s)}{K(s)} J_W(s)$$
(45)

$$\overline{P_A}(s) = \frac{\psi_A A(s)}{K(s)} J_A(s)$$
(46)

where,

$$K(s) = s + \psi_{V} + \psi_{M} + \psi_{P} + \psi_{1A} + \psi_{1W} + \gamma_{Q} - \psi_{V} \overline{S}_{V}(s) - \psi_{P} \overline{S}_{P}(s) - \psi_{M} \overline{S}_{M}(s) - \gamma_{Q} \overline{S}_{QR}(s) - \left[\gamma_{Q} \overline{S}_{QR}(s) + \psi_{A} \overline{S}_{A}(s)\right] \frac{\psi_{1A}}{C_{1}} - \left[\gamma_{Q} \overline{S}_{QR}(s) + \psi_{W} \overline{S}_{W}(s)\right] \frac{\psi_{1W}}{c_{2}} - \psi_{Q} \gamma_{Q} \overline{S}_{Q}(s) \left[1 + \frac{\psi_{1W}}{C_{1}} + \frac{\psi_{1A}}{C_{2}}\right] J_{QR}(s)$$

$$(47)$$

$$J_{i}(s) = \frac{1 - S_{v}(s)}{s}, \text{ for } i = V, P, M, QR, Q, A, W$$
(48)

$$J_{QR}(s) = \frac{1 - S_{QR}(s)}{s + \psi_Q} \tag{49}$$

$$A(s) = \frac{\psi_{1A}}{C_1} \tag{50}$$

$$B(s) = \frac{\psi_{1W}}{C_2}$$
(51)

$$C_{1} = s + \psi_{V} + \psi_{M} + \psi_{P} + \psi_{A} + \psi_{W} + \gamma_{Q} - \psi_{V} \overline{S}_{V}(s) - \psi_{P} \overline{S}_{P}(s) - \psi_{W} \overline{S}_{W}(s)$$
(52)

$$C_{2} = s + \psi_{V} + \psi_{M} + \psi_{P} + \psi_{A} + \psi_{W} + \gamma_{Q} - \psi_{V} S_{V}(s) - \psi_{P} S_{P}(s) - \psi_{A} S_{A}(s)$$
(53)

$$\overline{S}_{i}(j) = \int_{0}^{\infty} \phi_{i}(j) \exp[-s_{j} - \int_{0}^{i} \phi_{i}(j)dj]dj, \text{ for } i = V, P, M, QR, Q, A, W \& j = x, y, r, q, h, g, u.$$
(54)

$$\phi_{M} = \exp\left[r^{\theta} + \left[\log\phi_{M}(r)\right]^{\theta}\right]^{1/\theta}$$
(55)
Also,

0,

$$\overline{P}_{up}(s) + \overline{P}_{down}(s) = \frac{1}{s}$$
(56)

(62)

To study the steady-state behavior of the system using Abel's lemma we have

$$\lim_{s \to 0} \operatorname{sf}(s) = \lim_{t \to \infty} \operatorname{f}(t) = \operatorname{f}(\operatorname{say})$$

$$\overline{Pup}(s) = P_0(s) + P_{1W}(s) + P_{1A}(s)$$

$$P_0 = \frac{1}{\kappa'(0)}$$
(57)

$$\frac{R(0)}{B(0)}$$
(58)

$$P_{1W} = \frac{Z_{(0)}}{K(0)}$$
(59)

$$P_{1A} = \frac{A(0)}{\kappa'(0)}$$
(60)

where,

$$K'(0) = \left[\frac{d}{ds}K(s)\right]_{s=0}$$
(61)

 $T_i = -\overline{S}_i(0)_{=\text{Mean time to repair the ith failure}}$

$$A(0) = \frac{\psi_{1A}}{\psi_M + \psi_A + \gamma_Q} \tag{63}$$

$$B(0) = \frac{\psi_{1W}}{\psi_M + \psi_A + \gamma_Q} \tag{64}$$

$$\underline{Lim}J_{QR}(s) = \frac{1}{\psi_Q}M_{QR}$$
(As s tends to 0)
(65)

$$\mathbf{S}_{\phi_{i}}(j) = \frac{\phi_{i}}{\mathbf{j} + \phi_{i}}$$
(65)

$$\overline{\mathbf{R}}(\mathbf{s}) = \frac{1}{s + \psi_v + \psi_P + \psi_{1A} + \psi_{1W} + \psi_M + \gamma_Q}$$

where R(s) is the Laplace transform of the reliability function.

The reliability of the transit system is obtained as:

$$R(t) = \exp[-(\psi_{V} + \psi_{M} + \psi_{P} + \psi_{1A} + \psi_{1W} + \gamma_{Q}) *t]$$
(67)

The mean time to failure of the system is given by,

$$MTTF = Lim\overline{R}(s) = \int_0^\infty R(t)dt$$
$$MTTF = \frac{1}{\psi_V + \psi_M + \psi_P + \psi_{1A} + \psi_{1W} + \gamma_Q}$$

Availability of the system is given by,

$$\overline{Pup}(s) = P_0(s) + P_{1W}(s) + P_{1A}(s)$$
$$\overline{Pup}(s) = \frac{1}{K(s)} [1 + B(s) + A(s)]$$
$$\overline{Pup}(s) = \frac{1 + \frac{.016}{s + .055}}{s + .054}$$

Taking inverse Laplace transforms, we have

$$Pup(t) = -16.e^{(-.055000000t)} + 17.e^{(-.054000000t)}$$
(69)

Sensitivity analysis is performed for monitoring changes in reliability and MTTF of the system with respect to workstations W1, W3, and risk factor γ_Q .

we obtain

$$\frac{\partial R(t)}{\partial \psi_{V}} = -te$$

$$\frac{\partial R(t)}{\partial R(t)} = \frac{\partial R(t)}{\partial R(t)} \qquad (70)$$

Also, we can get $\overline{\partial \psi_P}$ and $\overline{\partial \gamma_Q}$. $\frac{\partial}{\partial \psi_V} MTTF = -\frac{1}{(\psi_V + \psi_P + \psi_{1A} + \psi_{1W} + \psi_M + \gamma_Q)^2}$ (71)

Also, $\partial MTTF / \partial \psi_{P}$ and $\partial MTTF / \partial \gamma_{Q}$.

The profit function of the considered manufacturing system is given by

$$G(t) = K_1 \cdot \int_0^t P_{up}(t) dt - K_2 t$$

where, K1 and K2 are revenue and repair costs per unit time, respectively. Also

$$G(t) = K_{1} \int_{0}^{t} e^{(-(\psi_{v} + \psi_{P} + \psi_{1A} + \psi_{1W} + \psi_{M} + \gamma_{Q})t)} + \left[\frac{\psi_{1A} + \psi_{1W}}{\psi_{1A} + \psi_{1W} - \psi_{W} - \psi_{A}} \right] e^{(-(\psi_{v} + \psi_{P} + \psi_{1A} + \psi_{1W} + \psi_{M} + \gamma_{Q})t)} - \left[\frac{\psi_{1A} + \psi_{1W}}{\psi_{1A} + \psi_{1W} - \psi_{W} - \psi_{A}} \right] e^{(-(\psi_{v} + \psi_{P} + \psi_{A} + \psi_{W} + \psi_{M} + \gamma_{Q})t)} dt - K_{2}t$$

$$(72)$$

(68)

4. Results and discussion

To check more concrete behavior of the system, Numerical computation of reliability, availability, and profit function is done concerning time by keeping other parameter fixed and also MTTF of the system for different failure rates.

Figure 2 shows the movement of reliability with respect to time. It reveals that due to ignorance of the workstation W₅ in inspection, the reliability decreases with the passage of time. Figure 3 shows a rapid decrease in MTTF with an increment in Workstation W₁, W₃, and machine failure rate. It is also observed that in some instances MTTF is almost the same with respect to these three failure rates. Also, as the risk rate increases, the MTTF of the system decreases smoothly shown in figure 4. Figure 5 gives an idea about the availability of the system that decreases constantly as time increases.

Sensitivity analysis of system reliability is done for different workstations failure rates as shown in figures 6, 7, 8, and 9. Here we observe that the system has almost same sensitivity for W₁ workstation failure and risk rate, although machine failure and workstation W₂ come next in magnitude.



Finally, Figure 10 shows that the cost of the system increases in general with time.

Figure 2: Reliability Vs Time



Figure 3: MTTF Vs workstation W1, workstation W3 and Machine failure



Figure 4: MTTF Vs Risk Rate



Figure 5: Availability Vs Time



Figure 6: Sensitivity of system reliability with respect to workstation W₁ failure.



Figure 7: Sensitivity of system reliability with respect to workstation W₂ failure.



Figure 8: Sensitivity for MTTF with respect to $X1=\Psi_{V}$, $X2=\Psi_{P}$. $(X=X1=X2)(\Psi_{V}=\Psi_{P}=.001, .00201)$



Figure 9: Sensitivity for MTTF with respect to $X = \gamma_Q (\gamma_Q = .01, .02, ..., 1)$



Figure 10: Cost Vs Time

5. Conclusion

In this work, the operational behavior of a k-out of-n configuration system is discussed including risk factor using mathematical modelling technique. Also, a comparative analysis of reliability, availability, MTTF, risk, sensitivity, and profit function are done with time for different workstations. The proposed technique has an advantage of analyzing reliability of a complex manufacturing system in a more flexible way.

The study may help a manufacturing industry in:

- a. Handling resources and suppliers
- b. Planning of production strategies and maintenance policies
- c. Decision making.

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